

## THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: Kiyoshi IRINO et al.

Group Art Unit: 2815

Serial No.: 09/428,052

Examiner: Jose R. Diaz

Filed: October 27, 1999

Confirmation No.: 4139

For:

METHOD OF FABRICATING A SEMICONDUCTOR DEVICE

CONTAINING NITROGEN IN A GATE-OXIDE FILM (AS

AMENDED)

Attorney Docket Number: 970901A

Customer Number: 38834

## **AMENDMENT**

Commissioner for Patents P. O. Box 1450 Alexandria, VA 22313-1450

Date: August 1, 2005

Sir:

This paper is filed in response to the Office Action dated May 5, 2005.

Amendments to the Claims begin on page 2 of this paper.

Remarks begin on page 4 of this paper.